Pre Andt

Docket: 0756-2256

RABREED 7/11/01

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re New Patent Application of)	
Koichiro TANAKA)	
Japanese Priority Application 2000-024615) Attn: Applications	
Japanese Priority Date: February 2, 2000)	Branch
For:	BEAM HOMOGENIZER, LASER)	
	IRRADIATION APPARATUS,)	
	SEMICONDUCTOR DEVICE, AND)	
	METHOD OF FABRICATING THE)	
	SEMICONDUCTOR DEVICE) Dat	te: February 1, 2001

PRELIMINARY AMENDMENT

Honorable Assistant Commissioner for Patents

Washington, D.C. 20231

Sir:

Please preliminarily amend the subject application as follows:

IN THE SPECIFICATION:

Page 18, line 16, change "Figs. 13A and 13B" to --Figs. 13A, 13B and 13C--.

REMARKS

This application has been amended to correct the brief description of Figure 13.

NVA169407.1